



Silicon Based Devices for Hydrogen Production

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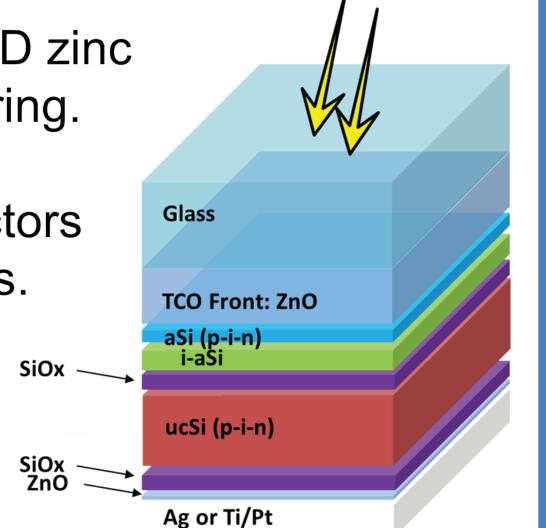
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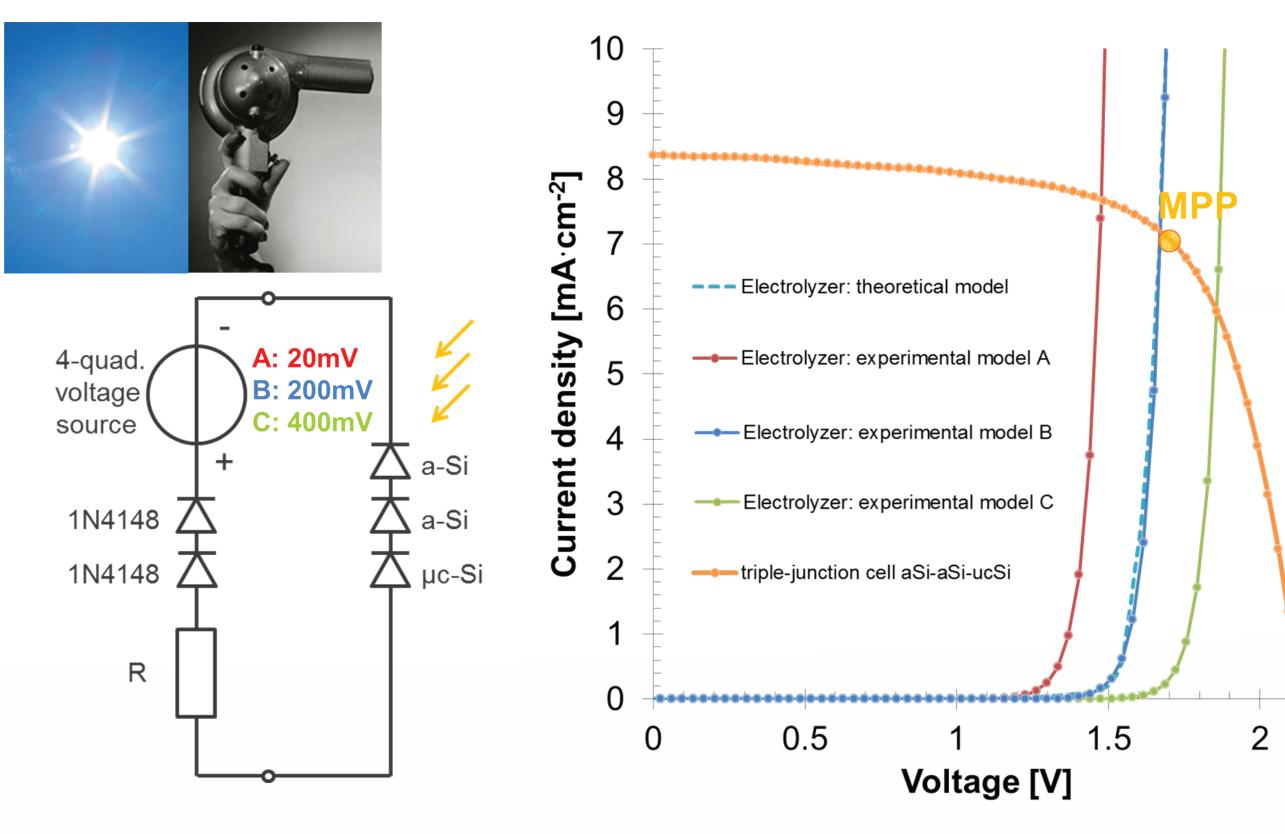
Constraint: Photovoltaic made from non-toxic and earth abundant materials (Si absorber) Challenge: Provide the voltage to break water molecules i.e. Voc > 2 V; Vmp > 1.8V

Thin-film silicon triple-junction solar cell

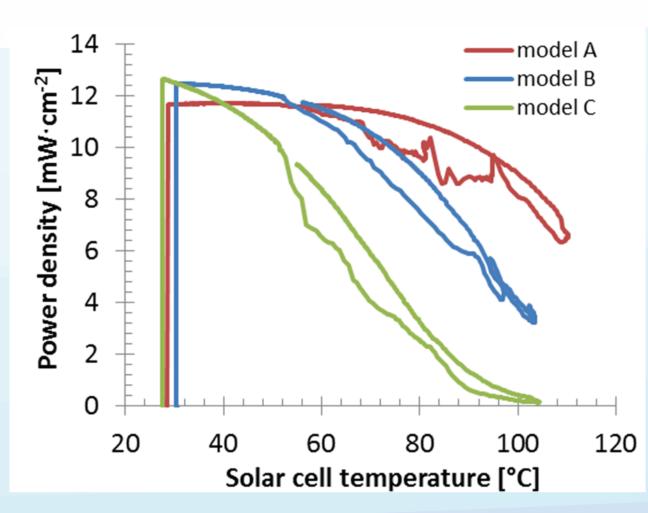
- Control of surface morphology of LPCVD zinc oxide →light-trapping via diffuse scattering.
- aSi/aSi/µcSi p-i-n junctions by PECVD
- Electronic transport through SiOx reflectors by PECVD via dendritic silicon filaments.
- Back metallization by PVD
- All processes @ typ. <200°C



Experimental study of thermal stability



- Thermal perturbation: dramatic loss with model C.
- Models A, B with OP at the left of MPP: <20% loss up to T_{cell}=65°C.

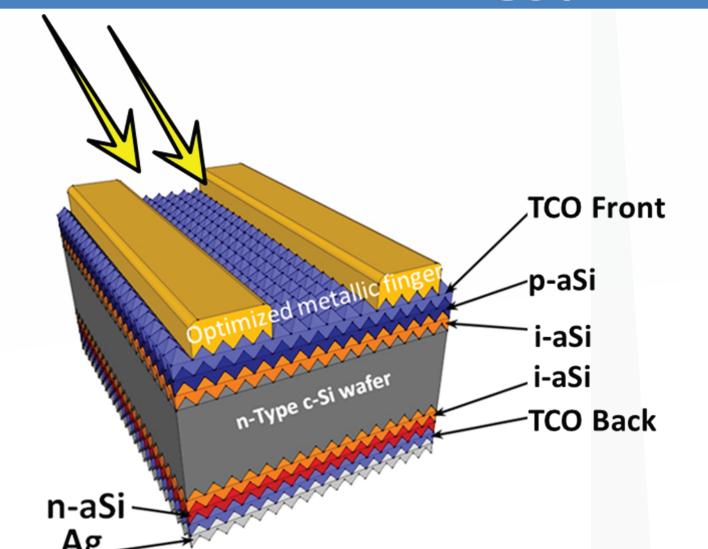


Wired and photocathode applications

	Jsc (mA/cm²)	Voc (mV)	FF (-)	Jmp (mA/cm²)	Vmp (mV)	Pmp (mW/cm²)						
Ī	7.14	2234	0.710	6.24	1815	11.3						
	1 -			Model J _{OP} (mA/cm²)	Model V _{OP} (mV)	Model SFE (%)						
	0.9	Sum: 23.3	4 mA/cm ²	6.59	1664	8.1						
ı	0.8 =	Jop = 6.59 mA/cm^2 \rightarrow Potential sun to										
	- 0.6 0.5 0.4 0.3 0.2 0.1	@13MHz 8.01 mA/cm ²	": CSem @13MHz 7.32 mA/cm ²	ncy:	• H ₂ formation at the Pt electrode -2 • Photoresponse under 1 sun: -3 5 mA/cm ² for ~20 h							
	300			00 90 gth [nm]	0		\rightarrow SFE = 6% -6 20 Time [h]					

c-Si HJT (hetero-junction technology)

- High quality n-type crystalline silicon (float zone)
- Wafer texturing
- HF cleaning
- Surface passivation with a-Si deposited by PECVD
- TCO deposition by PVD
- Front and back metallization
- All processes @ typ. <200°C



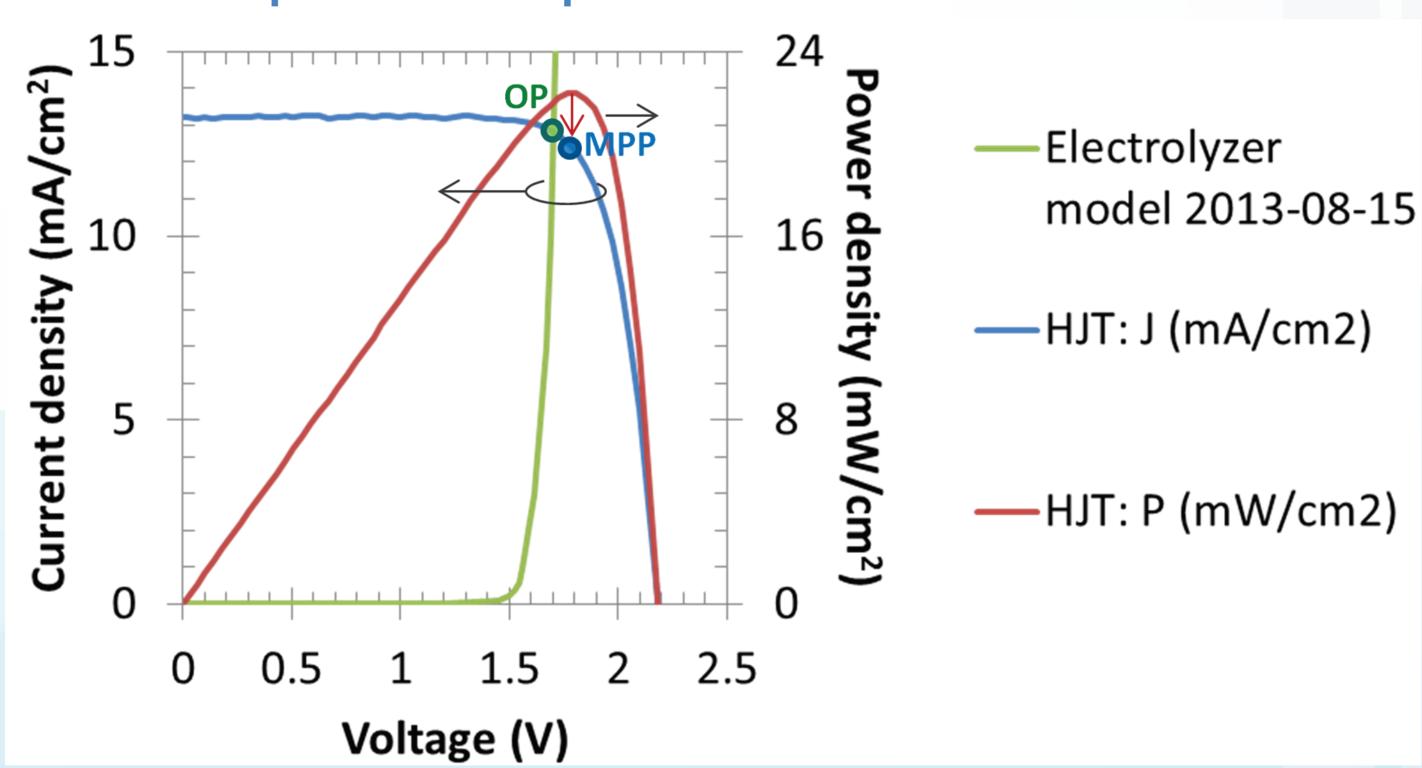
Motivation for 3 HJT cells in series

22.2	39.7	76.8		37.2
	Jsc (mA/cm²)		The second secon	Jmp (mA/cm²)

Baseline at CSEM for HJT. If 3 cells connected in series and no area lost, @1sun:

Voc = 2.18 V Jsc = 13.2 mA/cm²

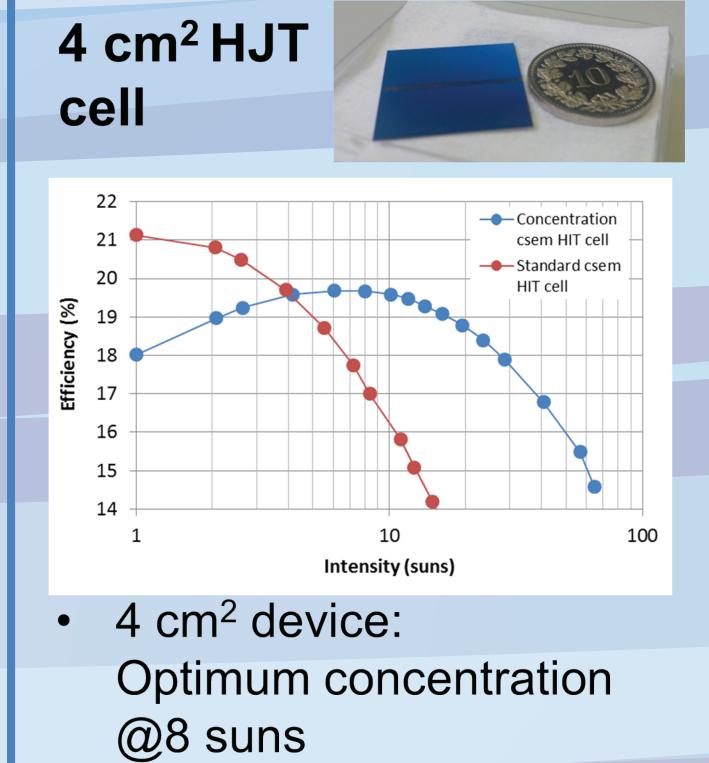
 $Vmp=1.79 V Jmp = 12.4 mA/cm^2$



Loading by model electrolyzer: Vop = 1.72 V; Jop = 12.8 mA/cm²

→ Potential SFE = 15.7%, and OP at the left hand side of MPP

Small c-Si HJT cells under concentration



• 0.9 cm² device:

Hint of a potential barrier at the front TCO / p a-Si interface

